Contract

Ultra-High Resolution Scanning thermal probe nanolithography with hybrid micro-nanolithography & 3D lithography capabilities

UNIVERSITY OF MANCHESTER

F03: Contract award notice
Notice identifier: 2021/S 000-024780
Procurement identifier (OCID): ocds-h6vhtk-02e48c
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Section I: Contracting authority

I.1) Name and addresses

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NUTS code

UKD33 - Manchester

Internet address(es)

Main address

https://www.staffnet.manchester.ac.uk/procurement/

I.4) Type of the contracting authority

Body governed by public law

I.5) Main activity

Education

Section II: Object

II.1) Scope of the procurement

II.1.1) Title

Ultra-High Resolution Scanning thermal probe nanolithography with hybrid micro-nanolithography & 3D lithography capabilities

Reference number

2021/1809/URSNL/RB

II.1.2) Main CPV code

- 38514200 - Scanning probe microscopes

II.1.3) Type of contract

Supplies

II.1.4) Short description

Ultra-High Resolution Scanning thermal probe nanolithography with hybrid micro-nanolithography & 3D lithography capabilities.

The AFM/thermal lithography system will enable patterning physical and chemical features with the nanoscale resolution, which is decisive for molecular devices and 2D-material devices. In addition, the integration of AFM, laser writing and thermal imaging has the potential for the development of new experimental techniques on correlation aspects of scanning based nanoscopy.

II.1.6) Information about lots

This contract is divided into lots: No

II.2) Description

II.2.2) Additional CPV code(s)

- 38000000 - Laboratory, optical and precision equipments (excl. glasses)

II.2.3) Place of performance

NUTS codes

- UKD3 - Greater Manchester

II.2.4) Description of the procurement

Ultra-High Resolution Scanning thermal probe nanolithography with hybrid micro-nanolithography & 3D lithography capabilities.

With the increasing demands on devices comprising nanoscale features with high resolution (e.g., in high performance computing, high density data storage, devices operating in THz range, sub-wavelength waveguides, photonic crystals and plasmonic structures, to name a few) and reducing power consumption by scaling electronic devices to sub-10 nm, new materials and new lithographic techniques are pivotal.

II.2.5) Award criteria

Quality criterion - Name: Quality / Weighting: 70

Cost criterion - Name: Cost / Weighting: 30

II.2.11) Information about options

Options: No

Section IV. Procedure

IV.1) Description

IV.1.1) Type of procedure

Open procedure

IV.1.8) Information about the Government Procurement Agreement (GPA)

The procurement is covered by the Government Procurement Agreement: Yes

IV.2) Administrative information

IV.2.1) Previous publication concerning this procedure

Notice number: 2021/S 000-023833

Section V. Award of contract

A contract/lot is awarded: No

V.1) Information on non-award

The contract/lot is not awarded

Other reasons (discontinuation of procedure)

Section VI. Complementary information

VI.4) Procedures for review

VI.4.1) Review body

The High Court of Justice of England

London

Country

United Kingdom